



Form 1449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary)	Atty Docket No.	Application No.:
	NOVLP029/NVLS-000495	10/067,520
	Applicant:	
	Shrinivasan et al.	
Filing Date	Group	
February 5, 2002	2811	

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
	A1						
	A2						
	A3						
	A4						
	A5						
	A6						
	A7						
	A8						
	A9						

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
NK	B1	WO02/01947	01/31/02	WIPO				
	B2	WO01/46999	06/28/01	WIPO				
	B3	WO01/33615	05/10/01	WIPO				
NK	B4	WO01/33613	05/10/01	WIPO				

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	C1	
	C2	
	C3	
Examiner	Date Considered	
	3/18/04	

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub- class	Filing Date

Foreign Patent or Published Foreign Patent Application


Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub- class	Translation	
							Yes	No

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
MK	A	Worm et al., "Spray Member and Method for Using the Same," U.S. Publication No. US 2003/0049939, Pub Date: March 13, 2003, 42 Pages
Examiner		Date Considered 3/18/04

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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U.S. Patent Documents

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Foreign Patent or Published Foreign Patent Application

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							Yes	No

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
<i>MK</i>	A	Costantini et al., "Supercritical Fluid Delivery and Recovery System for Semiconductor Wafer Processing", Pub. No.: US 2001/0050096 A1, Pub. Date: Dec. 13, 2001, Appl. No.: 09/837,507, Filed: April 18, 2001, pages 1-15
<i>MK</i>	B	Chandra et al., "Supercritical Fluid Cleaning Process for Precision Surfaces", Pub. No.: US 2002/0014257 A1, Pub Date: Feb. 7, 2002, Appl. No. 09/861,298, Filed: May 18, 2001, pages 1-21.
Examiner <i>[Signature]</i>		Date Considered <i>3/18/04</i>

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



06/12/02

Form 449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary)	Atty Docket No.	Application No.:
	NOVLP029/000495	10/067,520
	Applicant:	
	Shrinivasan et al.	
	Filing Date	Group
	February 5, 2002	2811

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
MK	A	Biberger et al., "High Pressure Processing Chamber for Semiconductor Substrate", Pub. No. US 2002/0046707 A1, Pub. Date: April 25, 2002, Appl. No.: 09/912,844, Filed: July 24, 2001, pp. 1-19.
Examiner <i>[Signature]</i>		Date Considered 3/18/04

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.